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PATENT & TRADEMARK

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RESPONSE UNDER 37 C.F.R. § 1.116  
**EXPEDITED PROCEDURE**  
**EXAMINING GROUP 2881**

**PATENT**  
Dkt. No.: 29273/559

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Yuko IWABUCHI, et al.  
SERIAL NO. : 10/083,481  
FILED : February 27, 2002  
FOR : METHOD AND AN APPARATUS OF AN INSPECTION SYSTEM  
USING AN ELECTRON BEAM  
GROUP ART : 2881  
EXAMINER : Jack I. Berman

RECEIVED  
APR 10 2003  
TECHNOLOGY CENTER 2800

ASSISTANT COMMISSIONER FOR  
PATENTS AND TRADEMARKS  
Washington D.C. 20231

**RESPONSE TO OFFICE ACTION**

Sir:

In response to the Office Action dated January 7, 2003, please amend the above-identified application as follows:

**IN THE CLAIMS:**

Please cancel claims 2, 3, 14 and 15.

Please amend claims 1, 4, 9 and 16 as follows:

1. (Amended) An inspection method for detecting a defect of a specimen by using an electron beam, said method comprising the steps of:  
deflecting said electron beam set at least 100nA beam current by taking a crossover as a fulcrum;  
applying a retarding voltage for decelerating the electron beam to said specimen; and  
changing the magnitude of said retarding voltage based on the nature of said specimen.

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